

Title (en)

METHOD AND DEVICE FOR DETERMINING THE THICKNESS OF A SEMICONDUCTOR MEMBRANE IN A MICROSTRUCTURE

Title (de)

VERFAHREN UND VORRICHTUNG ZUR ERMITTLUNG DER DICKE EINER HALBLEITERMEMBRAN IN EINER MIKROSTRUKTUR

Title (fr)

PROCEDE ET DISPOSITIF POUR DETERMINER L'EPAISSEUR D'UNE MEMBRANE DE TYPE SEMICONDUCTEUR DANS UNE MICROSTRUCTURE

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Application

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Abstract (en)

[origin: WO2006042528A1] The invention relates to a method and a device for determining the thicknesses of semiconductor membranes (1) by means of electrical measurements. Energy is coupled into the membrane in a defined manner and the membrane thickness is determined from the distribution or diffusion of the energy. A change of state of the membrane is carried out by measuring the electroconductivity by means of measuring resistances (3) on the membrane. The electroconductivity varies according to the temperature and the mechanical strain of the membrane, which both depend on the thickness of the membrane.

IPC 8 full level

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